

Issued: October 19, 2004

§ Customer No.: 27683

Title: High-Density Plasma Source
Using Excited Atoms

§ Real Party in Interest: Fujitsu
§ Semiconductor Limited and Fujitsu
§ Semiconductor America, Inc.

**PETITIONER POWER OF ATTORNEY PURSUANT TO 37 CFR 42.10(b)
FOR PETITION FOR *INTER PARTES* REVIEW**

Petitioners **Fujitsu Semiconductor Limited and Fujitsu Semiconductor America, Inc.** hereby appoints the Practitioner(s) associated with **Customer Number 27683**, as its attorney(s) to prosecute and to transact all business in the Patent Trial & Appeal Board of the United States Patent and Trademark Office connected with *Inter Partes* Review of the above-identified patent.

Please direct all communication regarding this Petition to **Customer Number 27683**:

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The undersigned is authorized to sign this Power of Attorney on behalf of the Petitioners.

Fujitsu Semiconductor Limited

By: 

Takashi Kikuma
Director, IP Licensing Department
Intellectual Property Unit

Fujitsu Semiconductor America, Inc.

By: 

Jesus Martinez
General Counsel & Corporate Secretary